

ASMJP.055C1



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoh et al.
Appl. No. : 10/759,925
Filed : January 16, 2004
For : SEMICONDUCTOR
PROCESSING WITH A REMOTE
PLASMA SOURCE FOR SELF-
CLEANING
Examiner : M. Kornakov
Group Art Unit : 1746

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

December 20, 2004

(Date)

Adeel S. Akhtar, Reg. No. 41,394

RESPONSE TO OFFICE ACTION

Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed on September 8, 2004, please amend the above-captioned application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 6 of this paper.

Amendments to the Drawings begin on page 9 of this paper. A "Replacement Sheet" for each sheet of drawings being amended can be found in the Appendix.

Remarks/Arguments begin on page 10 of this paper.